

Gino Putrino

List of Publications by Year in descending order

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32
papers

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docs citations

33
times ranked

528
citing authors

#	ARTICLE	IF	CITATIONS
1	Optical Microelectromechanical Systems Technologies for Spectrally Adaptive Sensing and Imaging. <i>Advanced Functional Materials</i> , 2022, 32, 2103153.	14.9	7
2	Mechanical properties of thermally evaporated germanium (Ge) and barium fluoride (BaF ₂) thin-films. <i>MRS Communications</i> , 2022, 12, 112-118.	1.8	2
3	Analytic approximation for the collapse of viscous tubes driven by surface tension and pressure difference. <i>Archive of Applied Mechanics</i> , 2022, 92, 1571.	2.2	0
4	MEMS for multispectral imaging. , 2022, , .		1
5	Large-area narrowband Fabry-Pérot interferometers for long-wavelength infrared spectral sensing. <i>Journal of Optical Microsystems</i> , 2022, 2, .	1.5	2
6	Pattern transferring of Prolift-100 polymer sacrificial layers with controlled sidewall profile. <i>Journal of Micromechanics and Microengineering</i> , 2021, 31, 075001.	2.6	0
7	Method for Increasing the Core Count and Area of High Density Optical Fiber Bundles. <i>IEEE Journal of Selected Topics in Quantum Electronics</i> , 2020, 26, 1-8.	2.9	46
8	MEMS based hydrogen sensing with parts-per-billion resolution. <i>Sensors and Actuators B: Chemical</i> , 2019, 281, 335-342.	7.8	18
9	Atomic force microscopy with integrated on-chip interferometric readout. <i>Ultramicroscopy</i> , 2019, 205, 75-83.	1.9	8
10	Large Area Silicon-Air-Silicon DBRs for Infrared Filter Applications. <i>Journal of Lightwave Technology</i> , 2019, 37, 769-779.	4.6	11
11	Multimodal atomic force microscopy with optimized higher eigenmode sensitivity using on-chip piezoelectric actuation and sensing. <i>Nanotechnology</i> , 2019, 30, 085503.	2.6	40
12	Ultrathin tunable terahertz absorbers based on electrostatically actuated metamaterial. , 2019, , .		0
13	Method for optical modelling of non-uniform and non-parallel multi-thin film MEMS optical filters and mirrors. , 2018, , .		0
14	Modelling and Characterization of the MEMS based filters for the spectroscopic imaging applications. , 2018, , .		1
15	MEMS-based Low SWaP Solutions for Multi/Hyperspectral Infrared Sensing and Imaging. , 2018, , .		1
16	A High Deposition Rate Amorphous-Silicon Process for Use as a Thick Sacrificial Layer in Surface-Micromachining. <i>Journal of Microelectromechanical Systems</i> , 2017, 26, 406-414.	2.5	4
17	Control of Sidewall Profile in Dry Plasma Etching of Polyimide. <i>Journal of Microelectromechanical Systems</i> , 2017, 26, 593-600.	2.5	7
18	Ultrathin tunable terahertz absorber based on MEMS-driven metamaterial. <i>Microsystems and Nanoengineering</i> , 2017, 3, 17033.	7.0	84

#	ARTICLE	IF	CITATIONS
19	Fast Tunable Terahertz Absorber Based on a MEMS-driven Metamaterial. , 2017, , .		1
20	An optical MEMS cross-bar switch. , 2016, , .		0
21	On-chip read-out of picomechanical motion under ambient conditions. Nanoscale, 2015, 7, 1927-1933.	5.6	14
22	Microcantilevers as a platform for the detection of hydrogen. , 2014, , .		0
23	Capturing the impulse response of a second order system. , 2014, , .		0
24	Low temperature through-wafer reactive ion etching for MEMS. , 2014, , .		0
25	An optically resonant position read-out system for MEMS gas sensors. , 2014, , .		0
26	Mercuryâ€“Cadmiumâ€“Telluride Waveguides â€“ A Novel Strategy for On-Chip Mid-Infrared Sensors. Analytical Chemistry, 2013, 85, 10648-10652.	6.5	41
27	Demonstration of a method for detecting MEMS suspended beam height.. , 2012, , .		0
28	A WDM Capable Integrated Optical Readout of a MEMS Sensor. Procedia Engineering, 2012, 47, 386-389.	1.2	0
29	An optically resonant, grating-based technique for the sensitive detection of MEMS cantilever beam height. , 2012, , .		0
30	Integrated Resonant Optical Readout Applicable to Large Arrays of MEMS Beams. IEEE Photonics Technology Letters, 2012, 24, 2243-2246.	2.5	6
31	Model and Analysis of a High Sensitivity Resonant Optical Read-Out Approach Suitable for Cantilever Sensor Arrays. Journal of Lightwave Technology, 2012, 30, 1863-1868.	4.6	17
32	Comparison of dynamic and static operation of a novel optical read-out technology for micromachined cantilever sensors. , 2010, , .		0